What is claimed is:



- 1. An etch/strip apparatus integrated with cleaning equipment, 1
- comprising: 2
- an etching line for etching and cleaning a substrate; 3
- a stripping line for stripping the substrate; and 4
- a cleaning line installed on the stripping line to clean and dry the 5
- substrate. 6

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- 2. The apparatus as claimed in claim 1, further comprising: 1
- an elevator for conveying the substrate from the stripping line to the 2 cleaning line.
 - 3. The apparatus as claimed in claim 1, further comprising:
 - a transfer for moving the substrate from the etching line to the stripping line.
 - 4. The apparatus as claimed in claim 1, further comprising:
 - a loader for feeding the substrate to the etching line; and 2
 - a unloader for receiving the substrate from the cleaning line. 3
 - 5. The apparatus as claimed in claim 1, wherein the etching line 1
 - includes: 2
 - an etch module for etching the substrate from the loader; and
 - a rinse module for cleaning the substrate fed from the etch module. 4

- 6. An integrated etch/strip/clean apparatus, co 1 an etching line for etching and cleaning a substrate; 2 a stripping line for stripping said substrate; and 3 a cleaning line integrated with said etching and stripping lines to 4 clean and dry the substrate. 5 7. The apparatus of claim 6, wherein said cleaning line is installed on 1 said stripping line. 2 8. The apparatus of claim 6, wherein said etching line includes: 1 ## ### 2 ### ### ### 3 an etch module; and a rinse module connected to said etch module. 1.0 (III. (III. 1.1) 9. The apparatus of claim 6, further comprising: <u>"</u> 2 <u>"</u> 2 a transfer module to transfer said substrate from said etching line to said stripping line. 12 10. The apparatus of claim 9, wherein said transfer module includes: 1 a pipe shower. 2 11. The apparatus of claim 6, further comprising: 1 an elevator to transfer said substrate from said stripping line to said 2
 - 1 12. The apparatus of claim 6, further comprising:

cleaning line.

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- a loader for loading the substrate to the etching ane; and
- a unloader for unloading the substrate from the cleaning line.
- 1 13. The apparatus of claim 12, wherein said loader includes at least
- one of a conveyor and a robot.
- 14. The apparatus of claim 12, wherein said unloader includes at least
- one of a conveyor and a robot.